

Day : Saturday
Date: 3/20/2004

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Time: 16:10:56

Inventor Name Search Result

Your Search was:

Last Name = AKIYAMA

First Name = KAZUYOSHI

Application#	Patent#	Status	Date Filed	Title	Inventor Name 27
10729005	Not Issued	020 1762 427/- unpublished	12/08/2003	PLASMA TREATMENT METHOD AND PLASMA TREATMENT APPARATUS	AKIYAMA, KAZUYOSHI IFW
10691519	Not Issued	030	10/24/2003	APPARATUS AND PROCESS FOR FORMING A DEPOSITED FILM	AKIYAMA, KAZUYOSHI
10691514	Not Issued	030 1763	10/24/2003 11/8/23	DEPOSITED FILM FORMING APPARATUS AND DEPOSITED FILM FORMING METHOD	AKIYAMA, KAZUYOSHI IFW C.I.-13 gpp. C.I.-18
10046318	6702898	150	01/16/2002	DEPOSITED FILM FORMING APPARATUS AND DEPOSITED FILM FORMING METHOD	AKIYAMA, KAZUYOSHI
10011776	Not Issued	041 0013	12/11/2001 438/1988	VACUUM PROCESSING METHOD, VACUUM PROCESSING APPARATUS, SEMICONDUCTOR DEVICE MANUFACTURING METHOD AND SEMICONDUCTOR DEVICE	AKIYAMA, KAZUYOSHI IFW 2003/0049558
09899188	Not Issued Allowed	092 1763	07/06/2001 11/8/2003E	PLASMA TREATMENT METHOD AND PLASMA TREATMENT APPARATUS	AKIYAMA, KAZUYOSHI IFW 1 2002/0098 632
09897961	6649020	150	07/05/2001	PLASMA PROCESSING METHOD AND APPARATUS	AKIYAMA, KAZUYOSHI
09851552	6486045	150	05/10/2001	APPARATUS AND METHOD FOR FORMING DEPOSITED FILM	AKIYAMA, KAZUYOSHI
09842154	6443191	150	04/26/2001	VACUUM PROCESSING METHODS	AKIYAMA, KAZUYOSHI
09652665	6413592	150	08/31/2000	METHOD FOR FORMING A DEPOSITED FILM BY	AKIYAMA, KAZUYOSHI

				PLASMA CHEMICAL VAPOR DEPOSITION	
<u>09616989</u>	<u>6350497</u>	150	07/14/2000	PLASMA PROCESSING METHOD	AKIYAMA, KAZUYOSHI
<u>09282462</u>	<u>6250251</u>	150	03/31/1999	VACUUM PROCESSING APPARATUS AND VACUUM PROCESSING METHOD	AKIYAMA, KAZUYOSHI
<u>09270211</u>	<u>6300225</u>	150	03/15/1999	PLASMA PROCESSING METHOD	AKIYAMA, KAZUYOSHI
<u>09219724</u>	<u>6347601</u>	150	12/23/1998	FILM FORMING APPARATUS	AKIYAMA, KAZUYOSHI
<u>09218086</u>	<u>6321759</u>	150	12/22/1998	METHOD FOR CLEANING A SUBSTRATE	AKIYAMA, KAZUYOSHI
<u>09184044</u>	<u>6165274</u>	150	11/02/1998	PLASMA PROCESSING APPARATUS AND METHOD	AKIYAMA, KAZUYOSHI
<u>09182002</u>	<u>6148763</u>	150	10/29/1998	DEPOSITED FILM FORMING APPARATUS AND DEPOSITED FILM FORMING PROCESS	AKIYAMA, KAZUYOSHI
<u>09157933</u>	<u>6155201</u>	150	09/22/1998	PLASMA PROCESSING APPARATUS AND PLASMA PROCESSING METHOD	AKIYAMA, KAZUYOSHI
<u>09112643</u>	<u>6336423</u>	150	07/09/1998	APPARATUS FOR FORMING A DEPOSITED FILM BY PLASMA CHEMICAL VAPOR DEPOSITION	AKIYAMA, KAZUYOSHI
<u>08988137</u>	<u>6152071</u>	150	12/10/1997	HIGH-FREQUENCY INTRODUCING MEANS, PLASMA TREATMENT APPARATUS, AND PLASMA TREATMENT METHOD	AKIYAMA, KAZUYOSHI
<u>08986577</u>	<u>6440504</u>	150	12/05/1997	VACUUM PROCESSING APPARATUS AND VACUUM PROCESSING METHOD	AKIYAMA, KAZUYOSHI
<u>08797829</u>	<u>6712019</u>	150	02/10/1997	APPARATUS AND PROCESS FOR FORMING A DEPOSITED FILM	AKIYAMA, KAZUYOSHI
<u>08506347</u>	<u>5817181</u>	150	07/24/1995	PROCESS FOR FORMING DEPOSITED FILM FOR LIGHT-RECEIVING MEMBER, LIGHT-RECEIVED MEMBER PRODUCED BY THE PROCESS DEPOSITED FILM FORMING APPARATUS, AND METHOD FOR CLEANING DEPOSITED FILM FORMING	AKIYAMA, KAZUYOSHI

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				APPARATUS	
<u>08264234</u>	<u>5582944</u>	150	06/22/1994	LIGHT RECEIVING MEMBER	AKIYAMA , KAZUYOSHI
<u>08138962</u>	<u>5455138</u>	150	10/21/1993	PROCESS FOR FORMING DEPOSITED FILM FOR LIGHT-RECEIVING MEMBER, LIGHT-RECEIVING MEMBER PRODUCED BY THE PROCESS, DEPOSITED FILM FORMING APPARATUS, AND METHOD FOR CLEANING DEPOSITED FILM FORMING APPARATUS	AKIYAMA , KAZUYOSHI
<u>08051358</u>	<u>5407768</u>	150	04/23/1993	LIGHT-RECEIVING MEMBER	AKIYAMA , KAZUYOSHI
<u>07890538</u>	Not Issued	166	05/28/1992	LIGHT-RECEIVING MEMBER	AKIYAMA , KAZUYOSHI

abd

Inventor Search Completed: No Records to Display.

	Last Name	First Name	
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1	L1	37	(("6702898") or ("6649020") or ("6486045") or ("6443191") or ("6413592") or ("6350497") or ("6250251") or ("6300225") or ("6347601") or ("6321759") or ("6165274") or ("6148763") or ("6155201") or ("6336423") or ("6152071") or ("6440504") or ("5817181") or ("5582944") or ("5455138") or ("5407768")) .PN.	USPAT; US-PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/03/20 16:50
2	L2	7877	((118/723E, 723ER, 723I, 723IR) or (427/569-579, 488- 491, 535-539)) .CCL S.	USPAT; US-PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/03/20 16:52
3	L3	440	2 and (electrode same impedance)	USPAT; US-PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/03/20 16:53

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	L #	Hits	Search Text	DBs	Time Stamp
1	L1	43	("4265991" "4788120" "5382311" "5405448" "5414324" "5433790" "5443689" "5447595" "5472509" "5500256" "5512510" "5520142" "5523261" "5563812" "5569350" "5591268" "5605576" "5665166") .PN.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/03/19 12:59
2	L2	3	("20020020357") .PN.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/03/19 13:00

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